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- An apparatus for switching electrical current, comprising: 1 .
- 2 a) an ohmically isolated island comprised of material having a band gap, wherein the island is 3 sufficiently large such that electron energy levels within the island are separated by less than 100 meV; 4
- b) a source contact; 5
 - c) a first tunnel junction barrier disposed between the island and the source contact, wherein the first tunnel junction barrier has a thickness and cross sectional area selected such that a first tunnel junction formed by the source contact, the first tunnel junction barrier and the island has a resistance less than a quantum resistance;
 - d) a drain contact;
 - e) a second tunnel junction barrier disposed between the island and the drain contact, wherein the second tunnel junction barrier has a thickness and cross sectional area selected such that a second tunnel junction formed by the drain contact, the second tunnel junction barrier and the island has a resistance less than the quantum resistance;
 - f) a gate electrode capacitively coupled to the island.
- The apparatus of claim 1 wherein the island comprises semiconductor material selected 1 2.
- 2 from the group consisting of silicon and germanium.
- 3. 1 The apparatus of claim 1 wherein the first tunnel junction and second tunnel junction 2 each have resistances less than 10 KOhms.

- The apparatus of claim 1 wherein the first tunnel junction and second tunnel junction 1
- 2 each have resistances less than 1 KOhms.
- 5. The apparatus of claim 1 wherein the first tunnel junction and second tunnel junction 1 each have resistances less than 100 Ohms. 2
- 1 The apparatus of claim 1 wherein the first tunnel junction barrier and second tunnel
- 2 junction barrier each have a thickness less than 24 Angstroms and a cross sectional area
- greater than 0.04 microns² 3

- 7. The apparatus of claim 1 wherein the first tunnel junction barrier and second tunnel junction barrier each have a thickness less than 18 Angstroms and a cross sectional area greater than 0.01 microns²
- The apparatus of claim 1 wherein the first tunnel junction barrier and second tunnel junction barrier each have a thickness less than 12 Angstroms and a cross sectional area greater than 0.0025 microns².
- 1 9. The apparatus of claim 1 wherein the first and second tunnel junction barriers comprise
- insulator material selected from the group consisting of silicon oxide and aluminum oxide 2
- 1 The apparatus of dlaim 1 further comprising a gate insulating layer disposed between the
- 2 gate electrode and the island.

- 1 11. The apparatus of claim 10 wherein a channel length between the first tunnel junction
- and second tunnel junction is in the range of 0.02-0.2 microns.
 - 1 12. A circuit, comprising:
 - a pair of tunnel junctions, each having a resistance less than or equal to approximately a
 - quantum resistance, separated by an island formed of a material having a non-uniform density
 - of energy states, each of the tunnel junctions being formed by the interconnection of the island
 - with a respective one of a pair of conductors through a tunnel junction barrier; and
 - a gate electrode capacitively coupled to the island.
 - 1 13. The circuit of claim 12 wherein the island is formed of a superconductor material.
 - 1 14. The circuit of claim 12 wherein the island is formed of a semiconductor material.
 - 15. The circuit of claim 14 wherein the semiconductor material comprises silicon.
 - 1 16. The circuit of claim 14 wherein the semiconductor material comprises germanium.
 - 1 17. The circuit of class 12 wherein the tunnel junction barriers are formed of an oxide of a
 - 2 material from which the conductors are made.
 - 1 18. The circuit of claim 17 wherein the gate electrode is made of the same material as the
 - 2 conductors.
 - 1 19. The circuit of claim 12 wherein the tunnel junction barriers are formed of an oxide of a
 - 2 material from which the island is made.
 - 20. The circuit of claim 12 wherein the tunnel junction barriers are formed of a material
 - 2 different from that of which the island is made and different from that of which the conductors
 - 3 are made.

- 21. The circuit of claim, 12 wherein the island is formed of an undoped material. 1
- 22. The circuit of claim 12 wherein the non-uniform density of energy states comprises at 1
- least one region that contains available energy states adjacent to at least one region that does
- not contain any available energy states.

- 23. A method, comprising forming a conduction path between a pair of tunnel junctions each
- having a resistance less than or equal to approximately a quantum resistance by shifting 2
- 3 energy states of an island formed of a material having a non-uniform density of such energy
- states, the island being disposed between the tunnel junctions. 4
- - 24. The method of claim 23 wherein the energy states of the island are shifted by application
 - or removal of a voltage through an electrode capacitively coupled to the island.
 - 25. The method of claim 24 further comprising passing a current through the conduction path
- via electrodes coupled to the tunnel junctions.